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In this paper, we present a critical review of on essential data on the physics and chemistry of low-pressure glow discharges of GeH4-that are used to deposit for the deposition of hydrogenated amorphous germanium films (a-Ge:H) films. Here, we analyze the sSurface processes and reaction probabilities of molecules, ions, and radicals are analyzed. -Gas phase elementary processing analysis is conducted performed on electron molecule collisions using An updated table of thermochemical data is used to analyze the gas phase elementary consisting offor ion-molecule collisions and neutral-neutral collisions.- Other electron and ion collisions, involving such as electron-ion and ion-ion recombination, electron attachment on-to radicals, and detachment of anion detachments, have are also been reported. <u>Study of c</u>Cluster growth kinetics in of dusty plasmas is conducted in are investigated orderto further enhance the applicability and relevance of this study. Experimental data orand theoretical estimates of electron collision cross sections, collision and reaction-rate constants, and transport coefficients are given. Further, these are discussed with regard to cross sections, collision and reaction rate constants, and transport coefficients. The Pfirsch-Schlüter diffusion and Spitzer terms are excluded from In-the perturbed distribution functions used in  $\delta f$  drift-kinetic Monte Carlo simulations to calculate we excluded explicitly the Pfirsch Schlüter diffusion off-diagonal neoclassical transport coefficients and Spitzer terms for in quasi-symmetric toroidal plasmas-, thus confirming geometric factor the constancy of geometric factor in the exact axisymmetric limit. Sugama and Horton investigated the -The formal-decomposition of the entropy-production rate with based on a the banana -- plateau and with the Pfirsch-Schlüter fluxes, -\_ derived by Sugama and Horton to theoretically explains the importance of excluding these collisional contributions. The numerically Numerically realized constancy of the geometric factor obtained with using DKE1 in the exact symmetric limit would be useful beneficial for conducting the simulation studies of on quasisymmetric-symmetric stellarators. -Moreover, The development of

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**Comment [A2]:** The en dash is used in place of a hyphen in cases where the paired elements carry equal weight or represent a parallel relationship, e.g., Carbon– Magnesium bond or Bose–Einstein statistics.

**Comment [A3]:** Hyphens are less commonly used in American English to connect prefixes to the main word.

**Comment [A4]:** The compound modifier is hyphenated when it appears before a noun in order to prevent any ambiguity. In this case, "banana-plateau" is the modifier that modifies the noun "fluxes."

**Comment [A5]:** To create an easy flow of ideas, transition words such as however, therefore, or moreover can be used. This usage enhances coherence of ideas in the paragraph and the manuscript on the whole.

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<u>techniques for</u> steady—state operation, heating, fueling, <u>diverters</u>, <u>diversion</u>, plasma—wall interaction, <u>and</u>-wall materials, advanced diagnostics for reactor—relevant plasma, blanket materials, and super conducting magnets <u>were\_are</u>\_discussed<u>as</u> inevitable key are also <u>discussed</u> in this study.

**Comment [A6]:** Unnecessary shifts in tense can confuse a reader and may not suit the context of the article. To maintain consistent tense usage, "were" is revised to "are."

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